	Application No.	Applicant(s)	
Notice of Allowability	10/826,286	LEE ET AL.	
	Examiner	Art Unit	
	Gregory R. Del Cotto	1751	
The MAILING DATE of this communication appeal claims being allowable, PROSECUTION ON THE MERITS IS nerewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIP of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this apport or other appropriate communication (GHTS). This application is subject to and MPEP 1308.	plication. If not include will be mailed in due	ed course. THIS
1. X This communication is responsive to Amend. filed 12/21/04.			
2. X The allowed claim(s) is/are 20-23, 27-31, 33-37, 41-51 renumbered 1-25.			
3. $igotimes$ The drawings filed on $4/19/04$ are accepted by the Examin	er.		
 Acknowledgment is made of a claim for foreign priority ur a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). 	been received. been received in Application No		ition from the
* Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file a reply IENT of this application.	complying with the red	quirements
5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give			IOTICE OF
6. CORRECTED DRAWINGS (as "replacement sheets") mus	st be submitted.		
(a) I including changes required by the Notice of Draftspers		948) attached	
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date			
(b) including changes required by the attached Examiner's Paper No./Mail Date	s Amendment / Comment or in the C	office action of	
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t	.84(c)) should be written on the drawir he header according to 37 CFR 1.121(c	ngs in the front (not the d).	back) of
 DEPOSIT OF and/or INFORMATION about the depo- attached Examiner's comment regarding REQUIREMENT 	sit of BIOLOGICAL MATERIAL r FOR THE DEPOSIT OF BIOLOGIC	nust be submitted. I AL MATERIAL.	Note the
Attachment(s) 1. Notice of References Cited (PTO-892)	5. ☐ Notice of Informal P	atent Application (PT	O-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ☑ Interview Summary		
3. Information Disclosure Statements (PTO-1449 or PTO/SB/0	Paper No./Mail Dat 98), 7. ⊠ Examiner's Amendr		
Paper No./Mail Date 4. ☐ Examiner's Comment Regarding Requirement for Deposit	8. X Examiner's Stateme	ent of Reasons for Allo	wance
of Biological Material	9.		
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	/1	#)

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EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Christopher Hayden on 3/3/05.

The application has been amended as follows:

The Claims:

In claim 20, line 1, delete "etching and resist material" and insert – resist and etching residue --.

In claim 20, line 2, delete "multi-level" and insert – wafer --.

In claim 20, line 3, delete the text beginning with "(a) forming..." and ending with "...and" in line 6.

In claim 20, line 7, delete "(d)".

In claim 20, line 8, delete "pattern".

In claim 20, line 25, after "of" insert - a chelating agent which is --.

In claim 23, line 1, delete "an alkyl" and insert – a C1-C6 straight, branched or cyclo alkyl --.

In claim 30, line 1, delete "26" and insert – 21 --.

In claim 31, line 1, delete "28" and insert – 27 --.

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In claim 35, line 1, delete "etching and resist material" and insert – resist and etching residue --.

In claim 35, line 2, delete "multi-level" and insert – wafer --.

In claim 35, line 3, delete the text beginning with "(a) forming..." and ending with "...and" in line 6.

In claim 35, line 7, delete "(d)".

In claim 35, line 8, delete "pattern".

In claim 35, line 20, after "water" insert --; and --.

In claim 35, line 38, delete "; and (d) water".

In claim 44, line 1, delete "further comprising ashing the resist and etching residue after the step of etching" and insert – wherein said cleaning composition is used to remove resist and etching residue which has been plasma ashed —.

In claim 48, line 1, delete "etching and resist material" and insert – resist and etching residue --.

In claim 48, line 2, delete "multi-level" and insert – wafer --.

In claim 48, line 3, delete the text beginning with "(a) forming..." and ending with "...and" in line 6.

In claim 48, line 7, delete "(d)".

In claim 48, line 8, delete "pattern".

In claim 48, line 20, after "water" insert --; and --.

In claim 50, line 2, delete "an alkyl" and insert – a C1-C6 straight, branched or cyclo alkyl --.

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REASONS FOR ALLOWANCE

The following is an examiner's statement of reasons for allowance:

Note that, Applicant's amendments, Applicant's arguments, the Examiner's Amendment, and the terminal disclaimer are sufficient to place the instant claims in condition for allowance. The Examiner asserts that all claim limitations are supported back to 08/078657, filed June 21, 1993. Additionally, note that the amendment submitted 4/19/04 which cancels claims 1-22, 24-26, and 40-63 and adds new claims 64-91 was not entered as a whole since claims which were intended to be canceled did not exist.

Of the references of record, the most pertinent is Nemes (GB 2,157,670) teaches a composition containing a hydroxylamine compound, a quinone, a dihydroxybezene, a dieminobenzene, or an aminohydroxybenzene compound, and a neutralizing amine.

The is an excellent composition for preventing corrosion in boiler water systems and other aqueous systems. However, Nemes does not teach a method for removing resist and etching residue from a wafer substrate as recited by the instant claims.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Gregory R. Del Cotto whose telephone number is (571)

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272-1312. The examiner can normally be reached on Mon. thru Fri. from 8:30 AM to 6:00 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Yogendra Gupta can be reached on (571) 272-1316. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Gregory R Del Cotto Primary Examiner Art Unit 1751

GRD March 3, 2005